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EE C247B - ME C218 Introduction to MEMS Design Spring 2014

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Lecture Module 9: Energy Methods

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Lecture Outline

- Reading: Senturia, Chpt. 10
- Lecture Topics:
 - ↳ Energy Methods
 - ↳ Virtual Work
 - ↳ Energy Formulations
 - ↳ Tapered Beam Example

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Energy Methods

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More General Geometries

- Euler-Bernoulli beam theory works well for simple geometries
- But how can we handle more complicated ones?
- **Example:** tapered cantilever beam
- **Objective:** Find an expression for displacement as a function of location x under a point load F applied at the tip of the free end of a cantilever with tapered width $W(x)$

Top view of cantilever's $W(x)$

$W(x) = W\left(1 - \frac{x}{2L_c}\right)$

50% taper top view

side view

$x = L_c$

F

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Solution: Use Principle of Virtual Work

- In an energy-conserving system (i.e., elastic materials), the energy stored in a body due to the quasi-static (i.e., slow) action of surface and body forces is equal to the work done by these forces ...
- Implication:** if we can formulate **stored energy** as a function of the deformation of a mechanical object, then we can determine how an object responds to a force by determining the shape the object must take in order to **minimize** the **difference U** between the stored energy and the work done by the forces:

$$U = \text{Stored Energy} - \text{Work Done}$$

- Key idea:** we don't have to reach $U = 0$ to produce a very useful, approximate *analytical* result for load-deflection

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More Visual Description ...

Same problem as before: Take a beam & apply a force:

- Apply force.
- Beam responds by bending.
- This force has done work: $W = F \cdot y(L_0)$
- Strain generated → This means the beam has received an influx of stored energy

⑤ then:
 $U = \text{Stored Energy} - \text{Work Done} \rightarrow 0$
 (When we choose the right shape! (This is how we get the beam's response to F!))

magnitude determined by its deformed shape

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Fundamentals: Energy Density

- Strain energy density: [J/m³]** $W(q) = \int_0^q \frac{Q}{C} dq$ → charging a capacitor from 0 → Q takes this much work
 ↳ To find work done in straining material → stored energy on a capacitor

This is a definition, so really can just say it's a definition.

$w = \int_0^{\epsilon_x} \sigma_x d\epsilon_x$ x-axis normal stress term
 $\sigma_x(\epsilon_x)$ → relates stress to strain @ position (x, y, z)
 $w = \int_0^{\epsilon_x} E \epsilon_x d\epsilon_x = \frac{1}{2} E \epsilon_x^2$

$W(q) = \int_0^q e(q) dq$ q = displacement, e = effort
 Generic Definition of Work

- Total strain energy [J]:**
 ↳ Integrate over all strains (normal and shear)

$$W = \iiint \left(\frac{1}{2} E (\epsilon_x^2 + \epsilon_y^2 + \epsilon_z^2) + \frac{1}{2} G (\gamma_{xy}^2 + \gamma_{xz}^2 + \gamma_{yz}^2) \right) dV$$

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Bending Energy Density

- First, find the bending energy dW_{bend} in an infinitesimal length dx :

$$dW_{\text{bend}} = W dx \int_{-h/2}^{h/2} \frac{1}{2} E \epsilon_x^2(y') dy'$$

$$\left[\frac{1}{R} = \frac{d^2 y}{dx^2}, \epsilon_x = \frac{y'}{R} \right] \Rightarrow \epsilon_x(y') = y' \frac{d^2 y}{dx^2}$$

$$dW_{\text{bend}} = W dx \int_{-h/2}^{h/2} \frac{1}{2} E \left(y' \frac{d^2 y}{dx^2} \right)^2 dy' = \frac{1}{2} E \left(\frac{Wh^3}{12} \right) \left(\frac{d^2 y}{dx^2} \right)^2 dx$$

$$\therefore W_{\text{bend}} = \frac{1}{2} E I_z \int_0^L \left(\frac{d^2 y}{dx^2} \right)^2 dx$$

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Energy Due to Axial Load

• Strain due to axial load S contributes an energy dW_{stretch} in length dx , since lengthening of the different element dx (to ds) results in a strain ϵ_x

Binomial Theorem

$$ds = [(dx)^2 + (dy)^2]^{1/2} = dx \left[1 + \left(\frac{dy}{dx}\right)^2 \right]^{1/2} \approx dx \left[1 + \frac{1}{2} \left(\frac{dy}{dx}\right)^2 \right]$$

$$\therefore \epsilon_x = \frac{ds - dx}{dx} = \frac{1}{2} \left(\frac{dy}{dx}\right)^2$$

Axial Strain Energy

$$dW_{\text{axial}} = S \epsilon_x dx = \frac{1}{2} S \left(\frac{dy}{dx}\right)^2 dx \Rightarrow W_{\text{axial}} = \frac{1}{2} S \int_0^L \left(\frac{dy}{dx}\right)^2 dx$$

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Shear Strain Energy

$$W_{\text{shear}} = \frac{3(EI_z)^2}{4GWh} \int_0^L \left(\frac{d^3y}{dx^3}\right)^2 dx$$

Shear Modulus

• See W.C. Albert, "Vibrating Quartz Crystal Beam Accelerometer," Proc. ISA Int. Instrumentation Symp., May 1982, pp. 33-44

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Applying the Principle of Virtual Work

• **Basic Procedure:**

- ↳ Guess the form of the beam deflection under the applied loads
- ↳ Vary the parameters in the beam deflection function in order to minimize:

Sum strain energies Assumes point load

$$U = \sum_j W_j - \sum_i F_i u_i$$

Displacement at point load

↳ Find minima by simply setting derivatives to zero

• See Senturia, pg. 244, for a general expression with distributed surface loads and body forces

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Example: Tapered Cantilever Beam

• **Objective:** Find an expression for displacement as a function of location x under a point load F applied at the tip of the free end of a cantilever with tapered width $W(x)$

Top view of cantilever's $W(x)$

Adjustable parameters: minimize U

• Start by guessing the solution $y(x) = c_2 x^2 + c_3 x^3$

- ↳ It should satisfy the boundary conditions
- ↳ The strain energy integrals shouldn't be too tedious
 - This might not matter much these days, though, since one could just use matlab or mathematica

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Strain Energy And Work By F

$U = \mathcal{W}_{\text{bend}} - F \cdot y(L_c)$

$$\mathcal{W}_{\text{bend}} = \frac{1}{2} E \int_0^{L_c} I_z(x) \left(\frac{d^2 y}{dx^2} \right)^2 dx \quad (\text{Bending Energy})$$

$$I_z(x) = \frac{W(x)h^3}{12} \quad \frac{d^2 y}{dx^2} = 2c_2 + 6c_3 x$$

(Using our guess)

$$W(x) = W \left(1 - \frac{x}{2L_c} \right)$$

Tip Deflection

$$= \frac{1}{24} E W h^3 \int_0^{L_c} \left(1 - \frac{x}{2L_c} \right) (2c_2 + 6c_3 x)^2 dx - F(c_2 L_c^2 + c_3 L_c^3)$$

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Find c_2 and c_3 That Minimize U

- Minimize U → basically, find the c_2 and c_3 that brings U closest to zero (which is what it would be if we had guessed correctly)
- The c_2 and c_3 that minimize U are the ones for which the partial derivatives of U with respect to them are zero:

$$\frac{\partial U}{\partial c_2} = 0 \quad \frac{\partial U}{\partial c_3} = 0$$

- Proceed:
 - First, evaluate the integral to get an expression for U:

$$U = E W h^3 \left\{ \frac{5c_3^2}{16} L_c^3 + \frac{c_2 c_3}{3} L_c^2 + \frac{c_2^2}{8} L_c \right\} - F(c_2 L_c^2 + c_3 L_c^3)$$

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Minimize U (cont)

- Evaluate the derivatives and set to zero:

$$\frac{\partial U}{\partial c_2} = 0 = \left(\frac{E W h^3}{3} c_3 - F \right) L_c^2 + \left(\frac{E W h^3}{4} c_2 \right) L_c$$

$$\frac{\partial U}{\partial c_3} = 0 = \left(\frac{5}{8} E W h^3 c_3 - F \right) L_c^3 + \left(\frac{E W h^3}{3} c_2 \right) L_c^2$$

- Solve the simultaneous equations to get c_2 and c_3 :

$$c_2 = \left(\frac{84}{13} \right) \frac{F L_c}{E W h^3} \quad c_3 = - \left(\frac{24}{13} \right) \frac{F}{E W h^3}$$

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The Virtual Work-Derived Solution

- And the solution:

$$y(x) = \left(\frac{24F}{13EWh^3} \right) \left(\left(\frac{7}{2} \right) L_c - x \right) x^2$$

- Solve for tip deflection and obtain the spring constant:

$$y(L_c) = \left(\frac{24F}{13EWh^3} \right) \left(\frac{5}{2} \right) L_c^3 \quad k_e = F / y(L_c) = \left(\frac{13EWh^3}{60L_c^3} \right)$$

- Compare with previous solution for constant-width cantilever beam (using Euler theory):

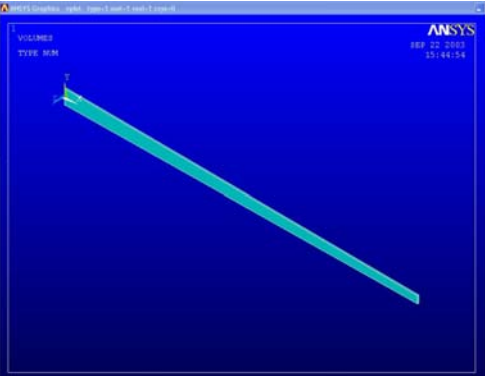
$$y(L_c) = \left(\frac{4F}{EWh^3} \right) L_c^3 \quad \longrightarrow \quad 13\% \text{ smaller than tapered-width case}$$

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Comparison With Finite Element Simulation

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- Below: ANSYS finite element model with
 - $L = 500 \mu\text{m}$ $W_{\text{base}} = 20 \mu\text{m}$ $E = 170 \text{ GPa}$
 - $h = 2 \mu\text{m}$ $W_{\text{tip}} = 10 \mu\text{m}$



The image shows a screenshot of an ANSYS simulation window. The window title is 'ANSYS Workbench - Job - Job1 - Job1 - Job1 - Job1'. The main area displays a 3D model of a cantilever beam, colored in a gradient from blue at the fixed base to red at the free tip, indicating stress distribution. The beam is fixed at the top left and extends downwards and to the right. The ANSYS logo and version information are visible in the top right corner of the window.

- Result:** (from static analysis)
 - $k = 0.471 \mu\text{N/m}$
- This matches the result from energy minimization to 3 significant figures

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Need a Better Approximation?

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- Add more terms to the polynomial
- Add other strain energy terms:
 - Shear: more significant as the beam gets shorter
 - Axial: more significant as deflections become larger
- Both of the above remedies make the math more complex, so encourage the use of math software, such as Mathematica, Matlab, or Maple
- Finite element analysis is really just energy minimization
- If this is the case, then why ever use energy minimization analytically (i.e., by hand)?
 - Analytical expressions, even approximate ones, give insight into parameter dependencies that FEA cannot
 - Can compare the importance of different terms
 - Should use in tandem with FEA for design

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